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PARALLEL, INDIVIDUALLY ADDRESSABLE PROBES FOR NANOLITHOGRAPHY

RELATED APPLICATIONS

This is a continuation of application Serial No. 10/008,719, filed
December 7, 2001, which claims priority of U.S. Provisional Application Serial
No. 60/307,976, filed July 26, 2001, *now Patent No. 6,642,129*

STATEMENT OF GOVERNMENT INTEREST

This invention was made with United States Government
assistance through Defense Advanced Research Projects Agency (DARPA)
Contract No. NW 0650 300 F 245. The Government has certain rights in this
invention.

FIELD OF THE INVENTION

The present invention relates generally to the art of efficient and
high-speed generation of fine surface patterns made of chemical resists or
biological substances using micromachined or microfabricated probes.

BACKGROUND OF THE INVENTION

High-throughput lithography and surface patterning with
extremely fine linewidths (e.g., on the order of 10-100 nm) are very important
for the future growth of the microelectronics industry and nanotechnology.